

FIG. 1(A)

FORMING STEP OF AMORPHOUS SEMICONDUCTOR FILM

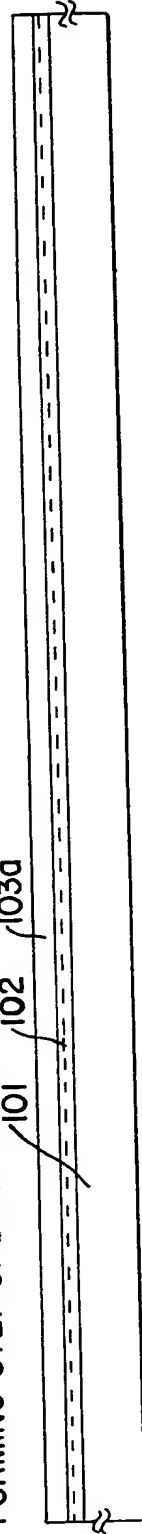


FIG. 1(B)

CRYSTALLIZATION STEP

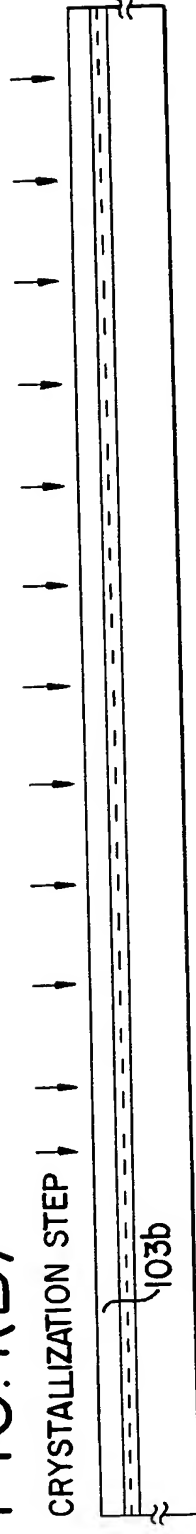


FIG. 1(C)

FORMING STEP OF MASK LAYER

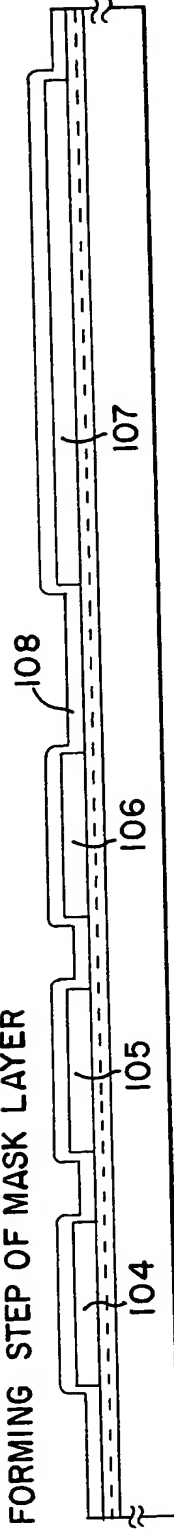


FIG. 1(D)

CHANNEL DOPING STEP

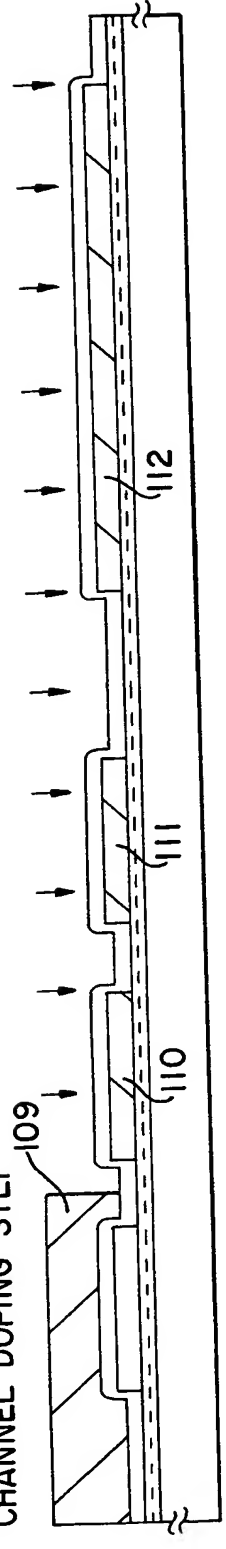


FIG. 2(A)

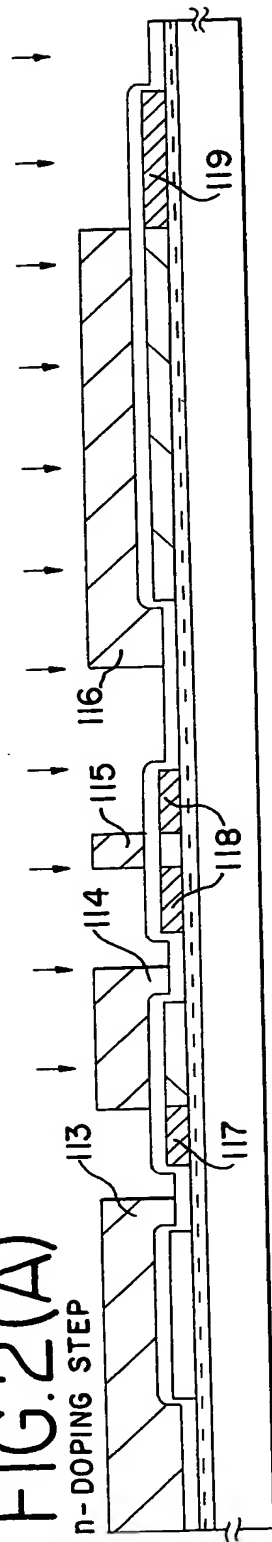


FIG. 2(B)

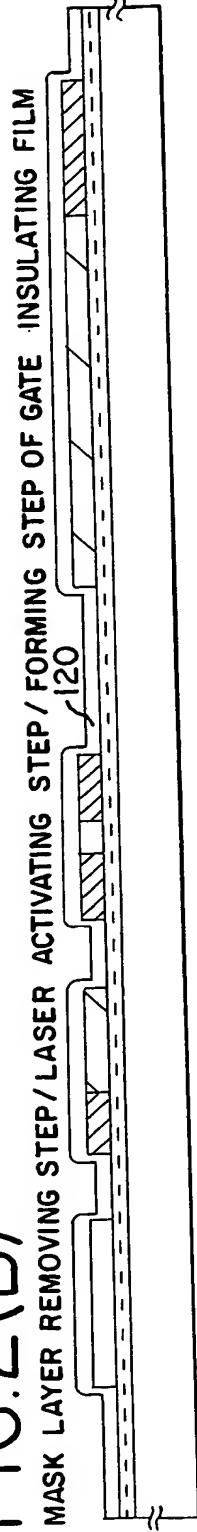


FIG. 2(C)

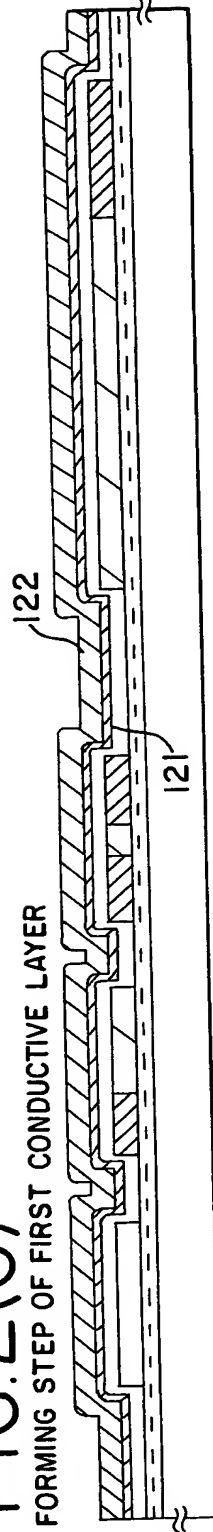


FIG. 2(D)

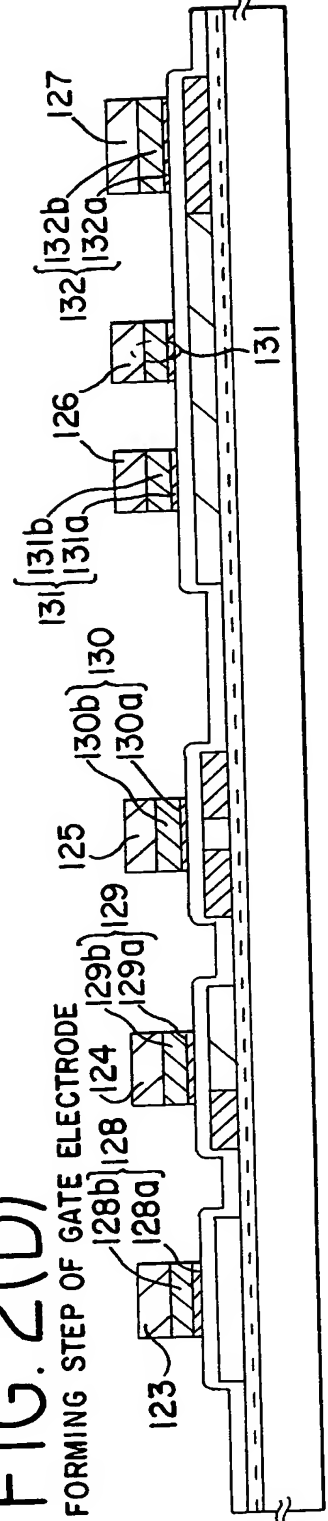


FIG. 3(A)

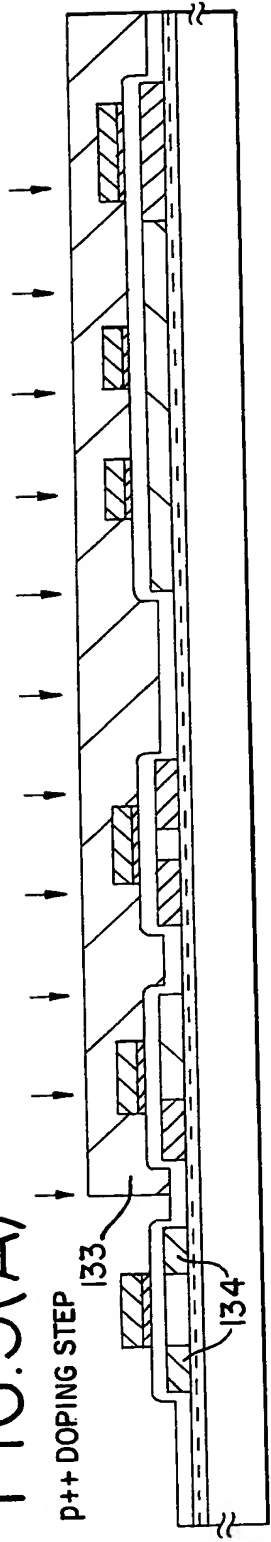


FIG. 3(B)

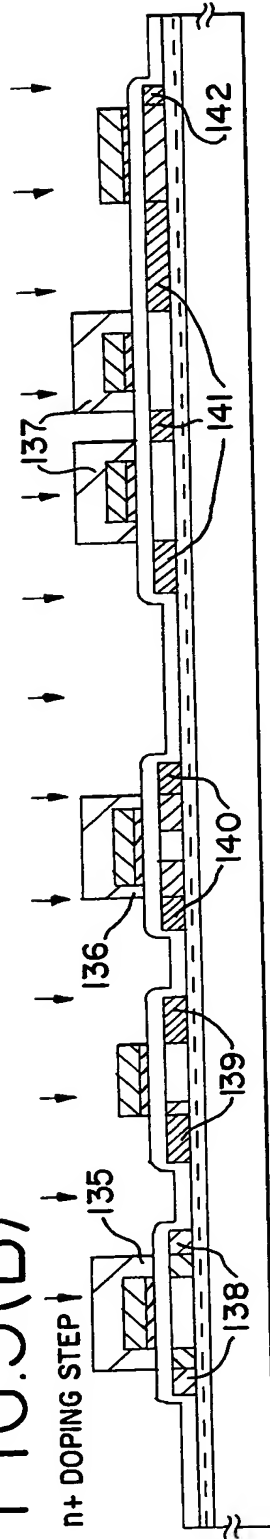


FIG. 3(C)

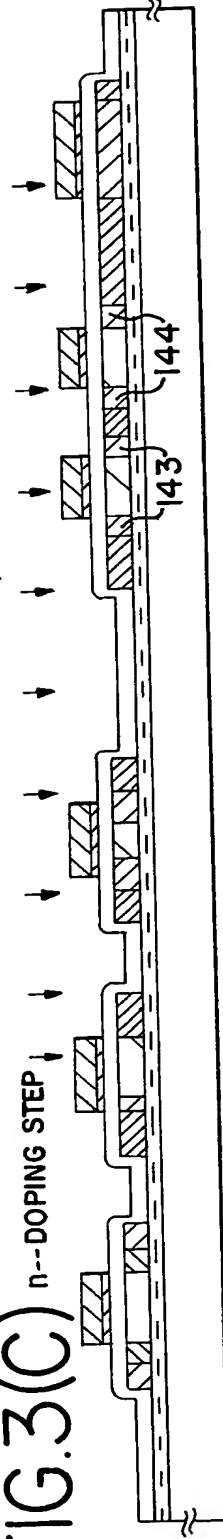
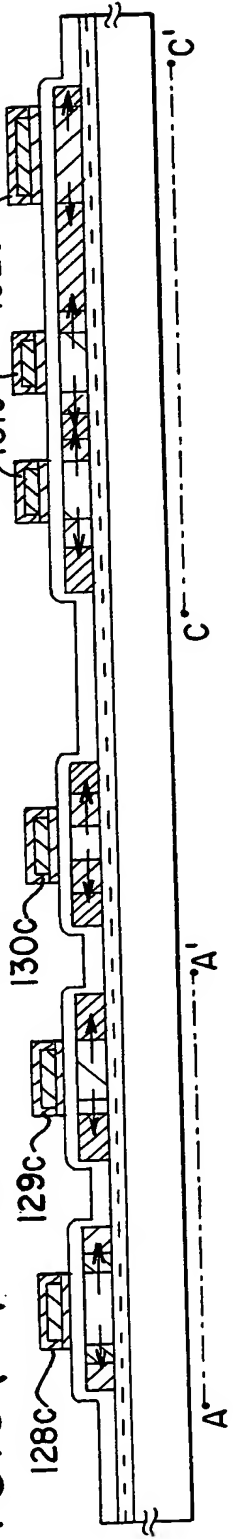


FIG. 3(D)

ACTIVATING (GETTERING) STEP / NITROGENATION STEP / HYDROGENATION STEP



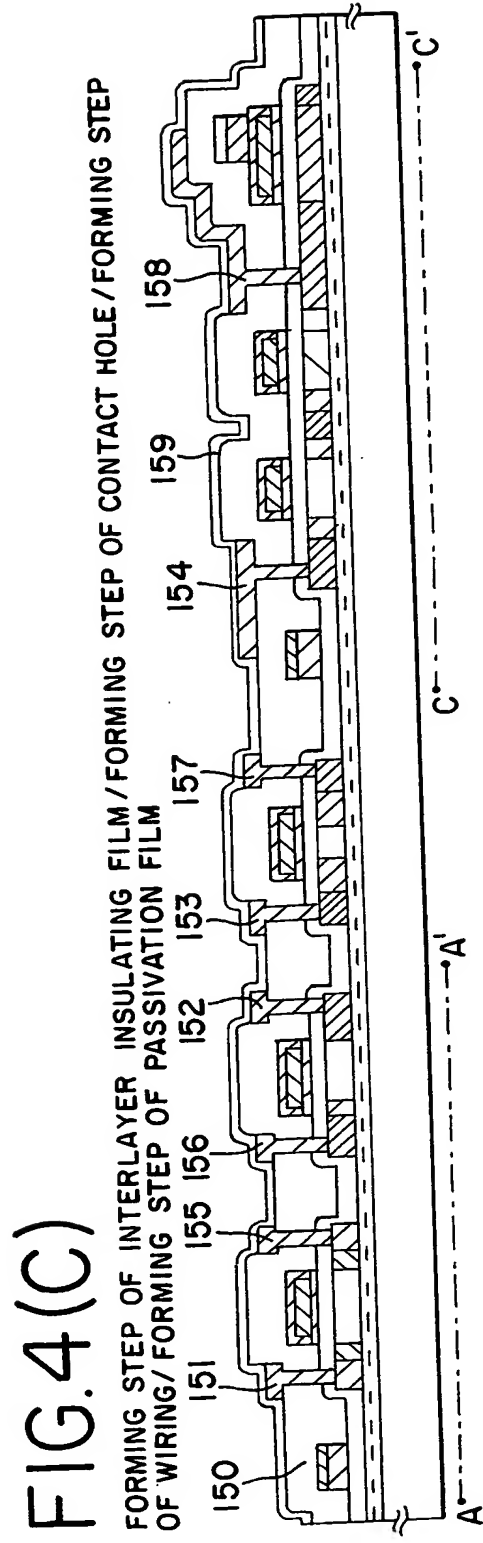
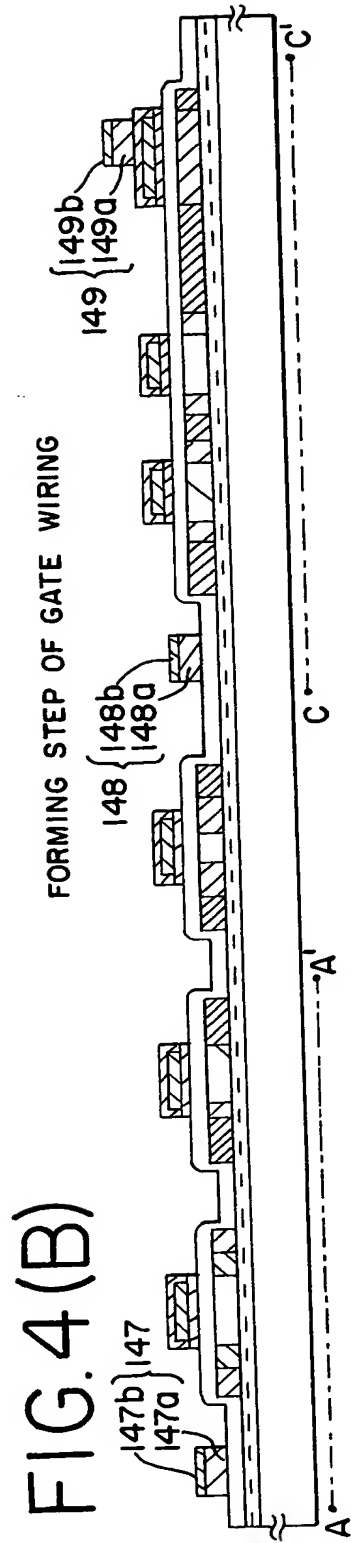
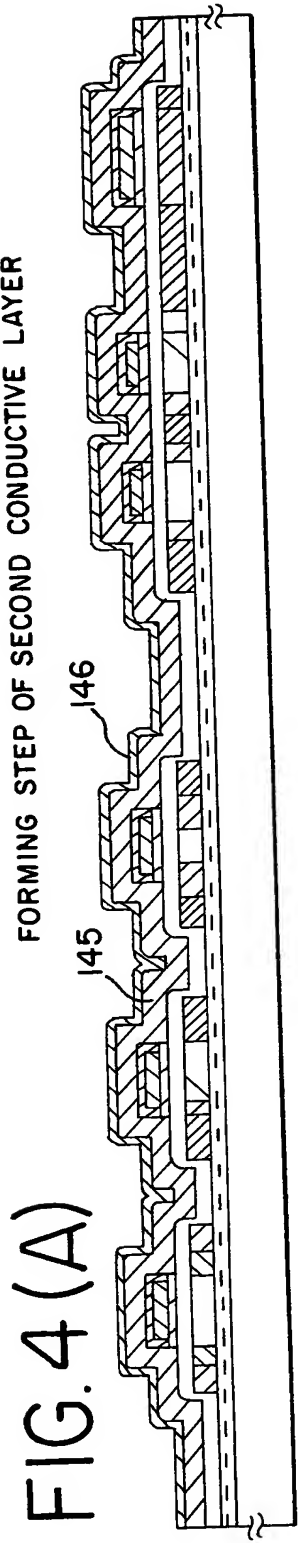


FIG. 5

FORMING STEP OF RESIN FILM / FORMING STEP OF CONTACT HOLE / FORMING STEP OF PIXEL ELECTRODE

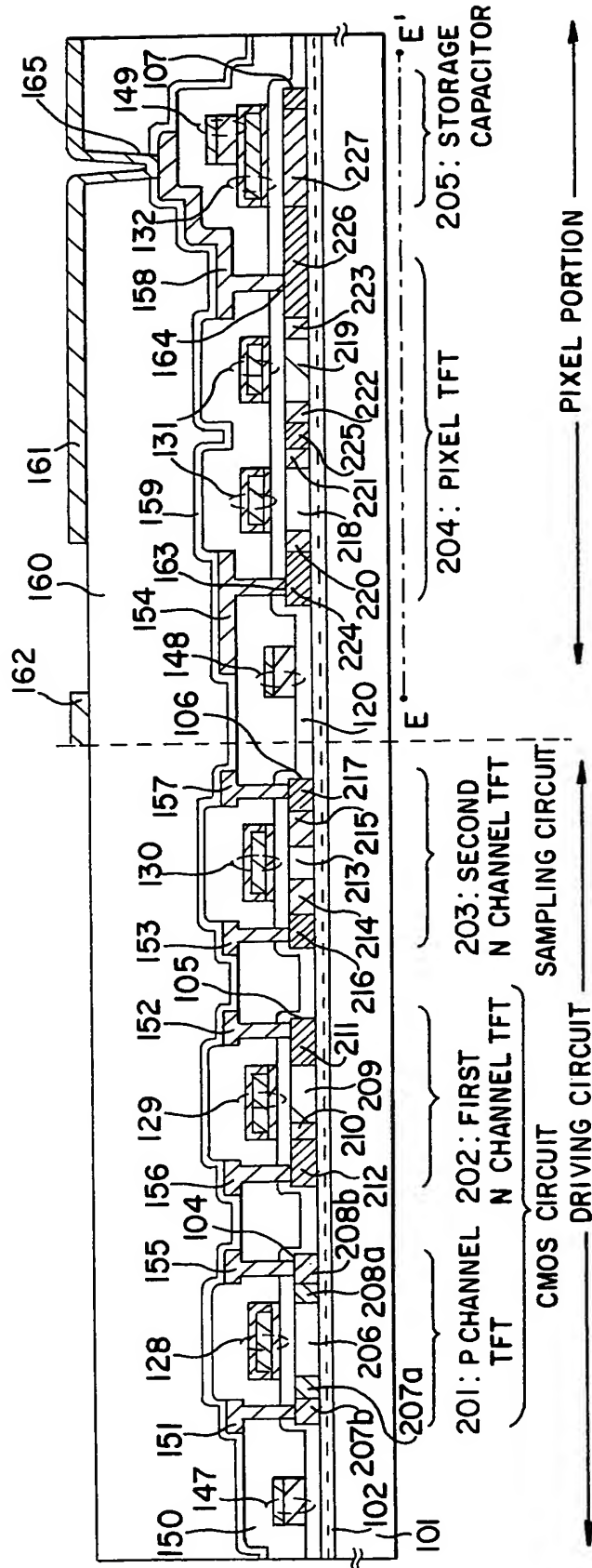


FIG.6(A)

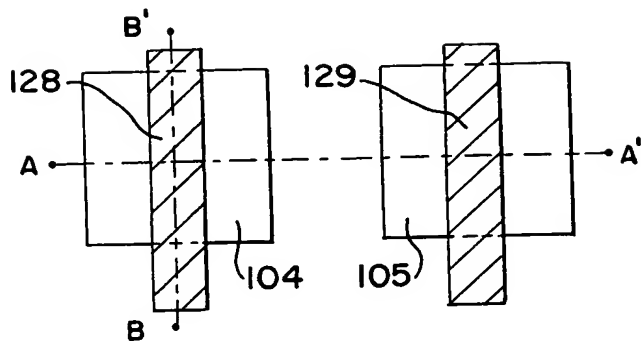


FIG.6(B)

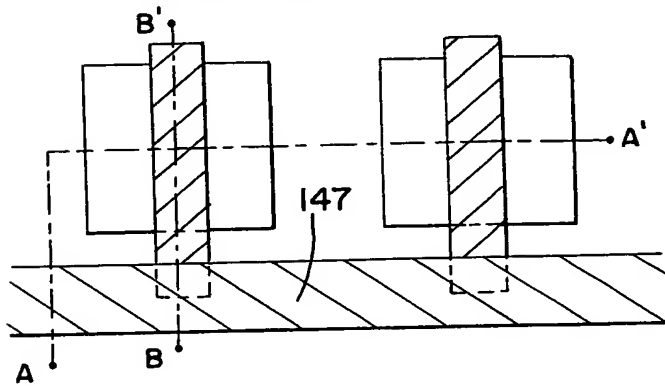


FIG.6(C)

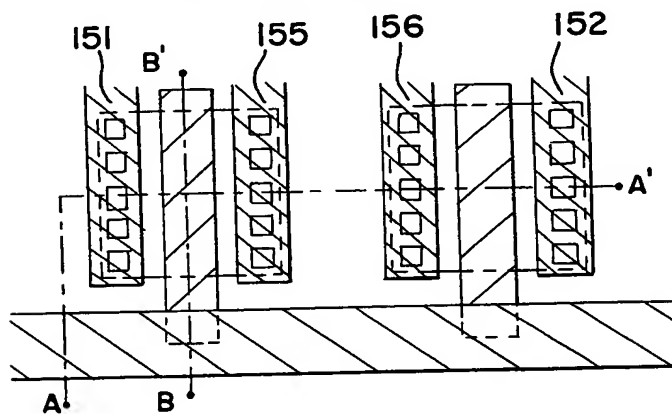


FIG.7(A)

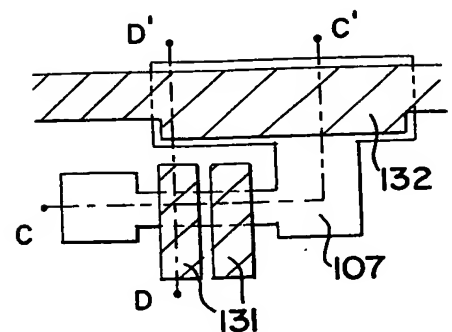


FIG.7(B)

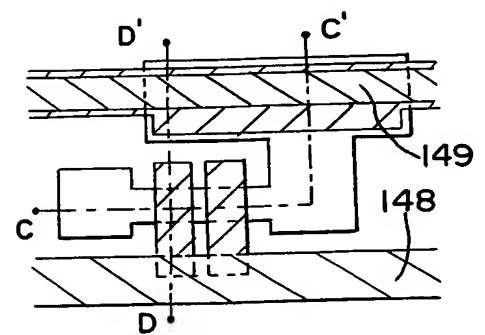


FIG.7(C)

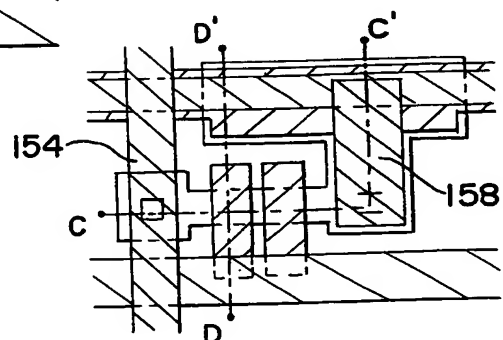


FIG.8(A)

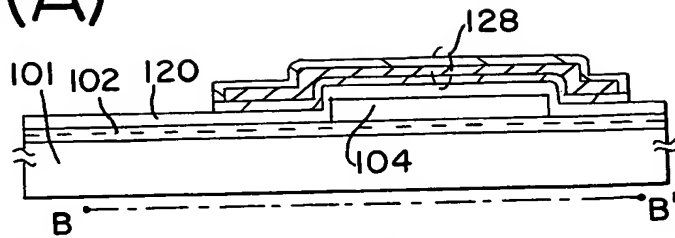


FIG.8(B)

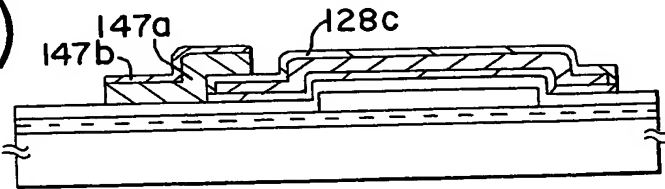


FIG. 8(C)

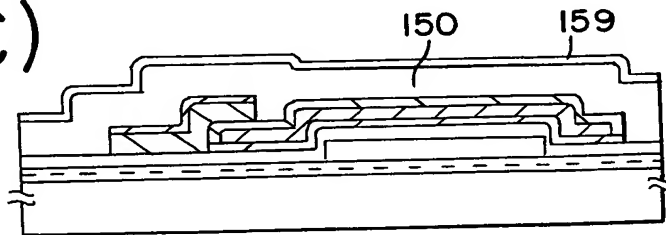


FIG.9(A)

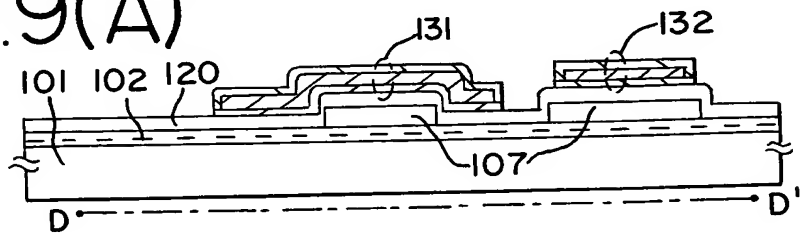


FIG.9(B)

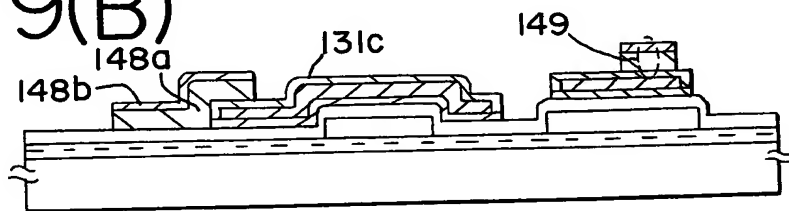


FIG. 9(C)

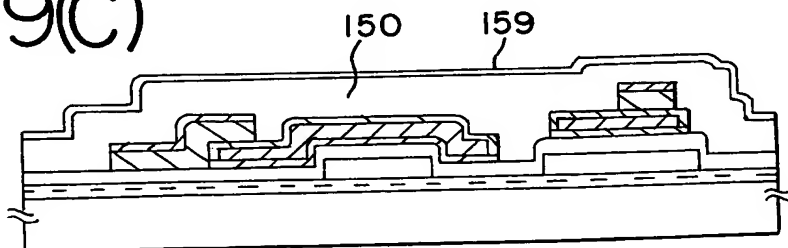


FIG. 10

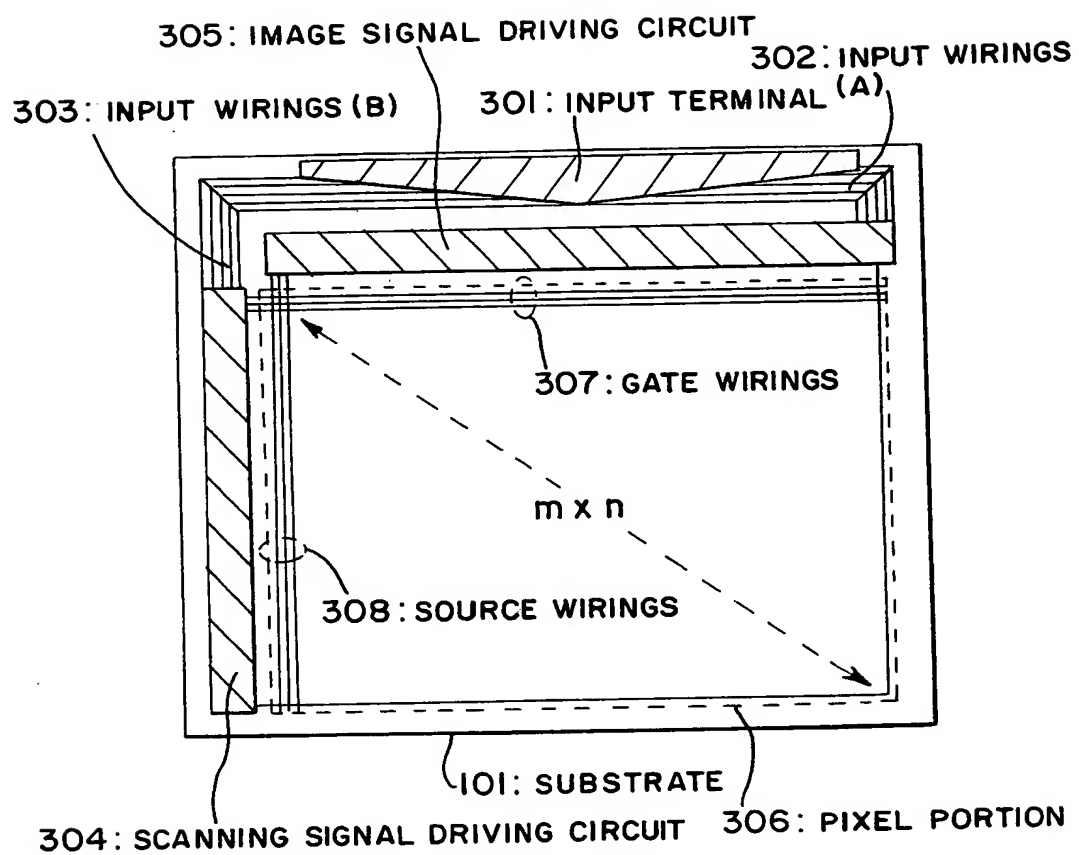


FIG. 11

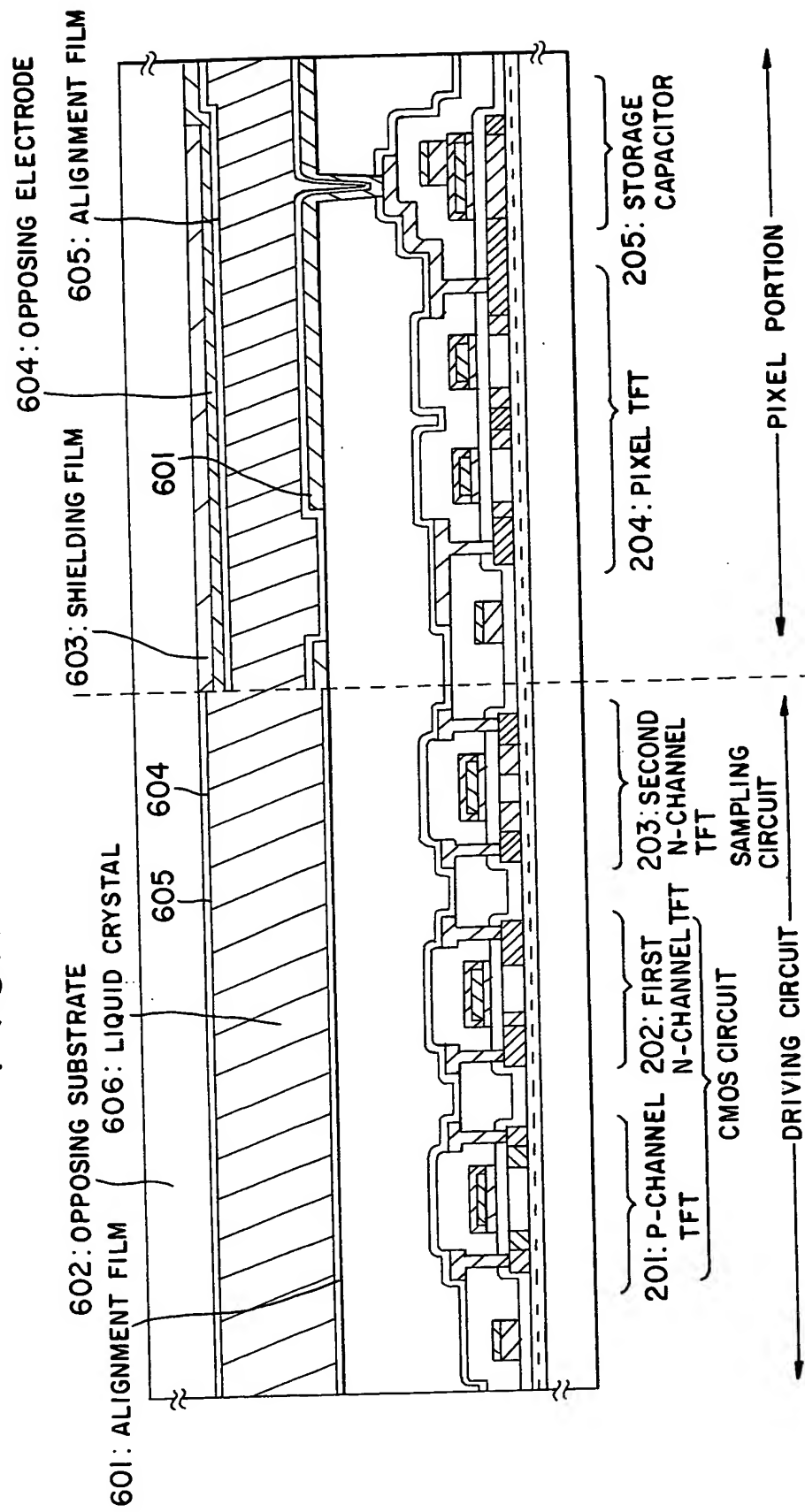


FIG. 12

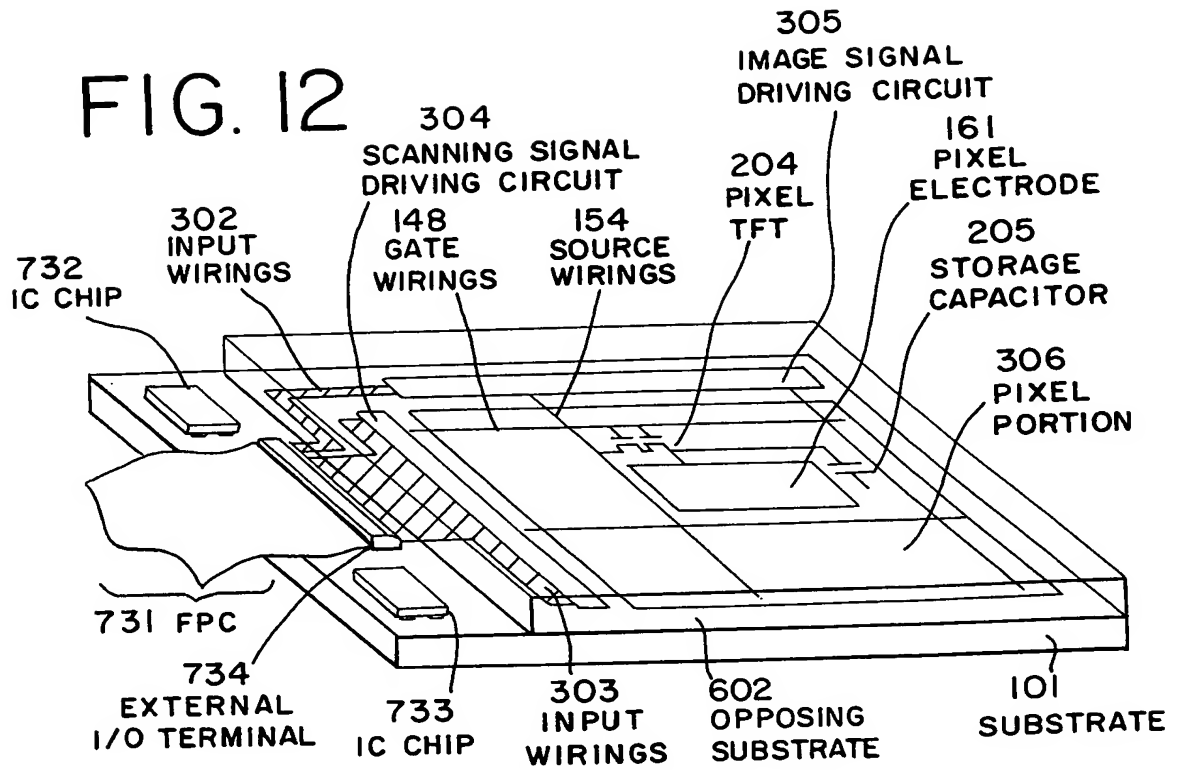


FIG. 13

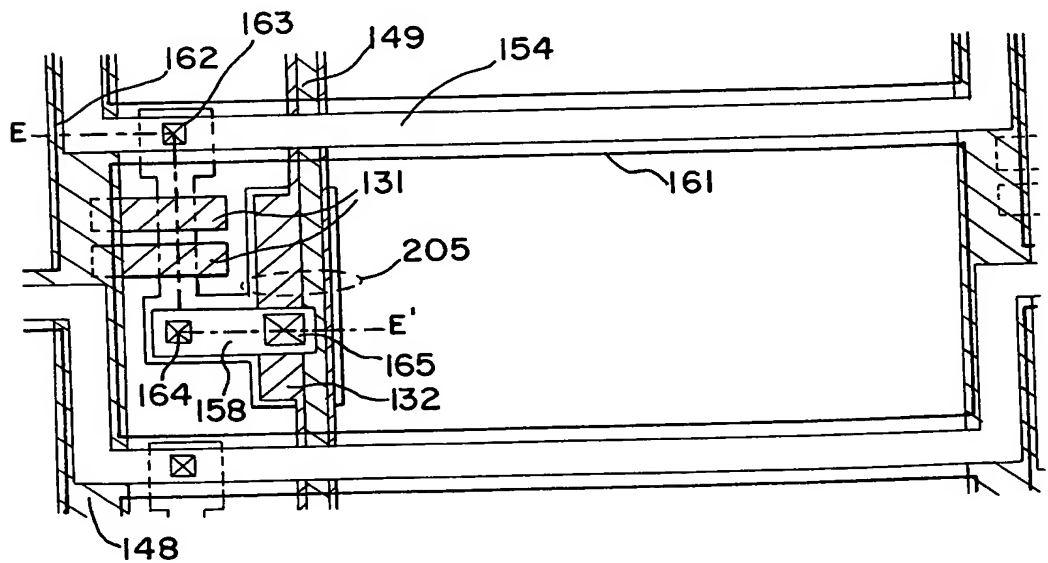


FIG.14

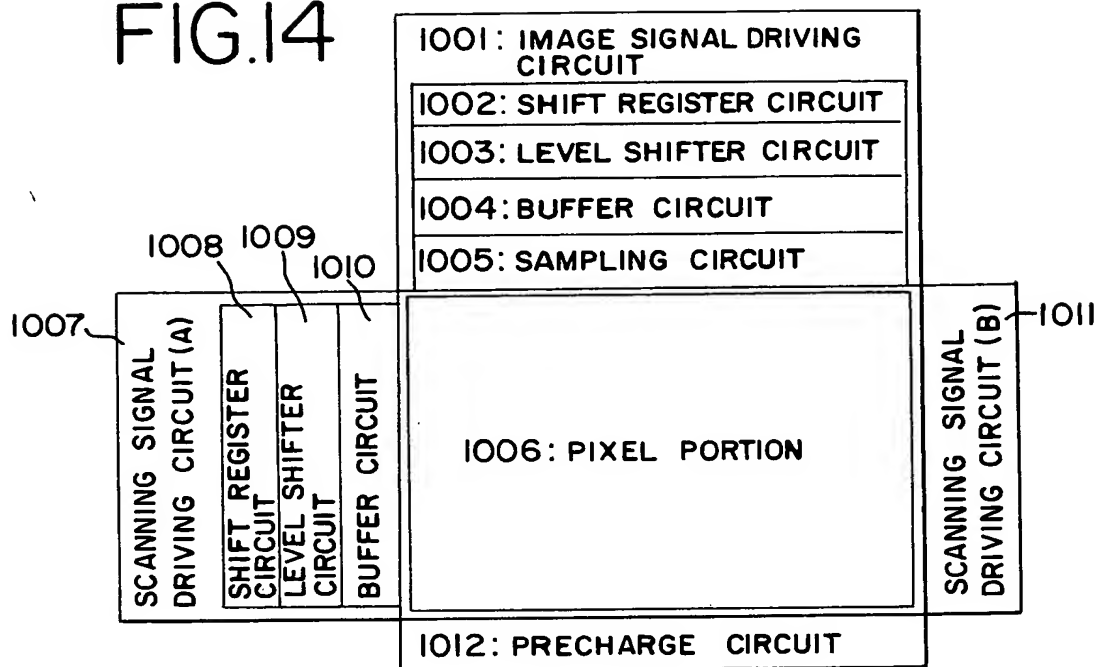


FIG.15(A)

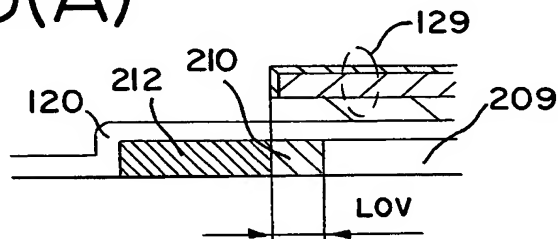


FIG.15(B)

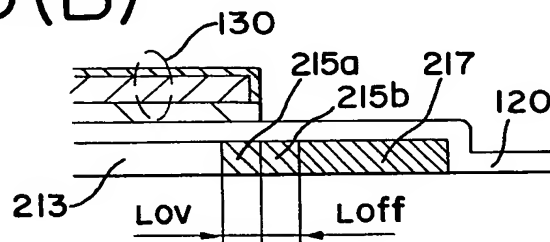


FIG.15(C)

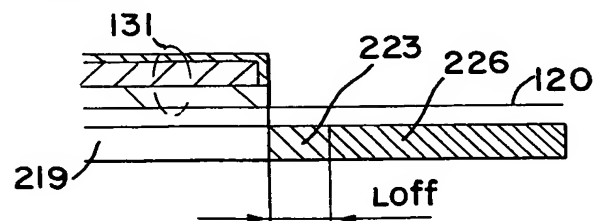


FIG.16(A)

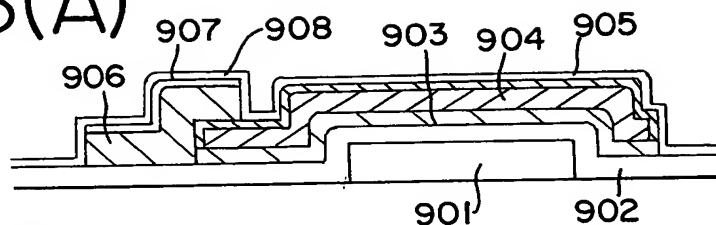


FIG.16(B)

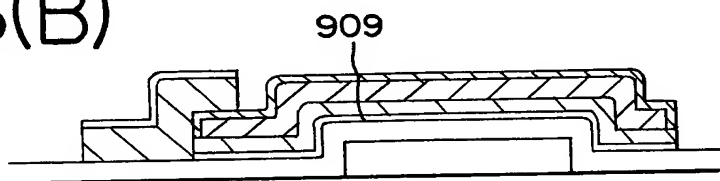


FIG.16(C)

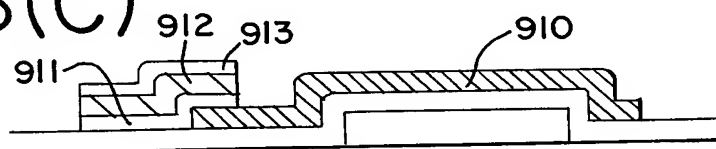


FIG.17(A)

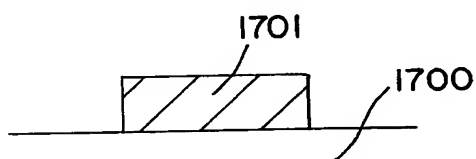


FIG.17(D)

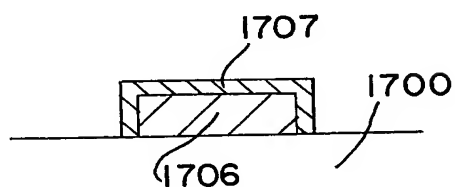


FIG.17(B)

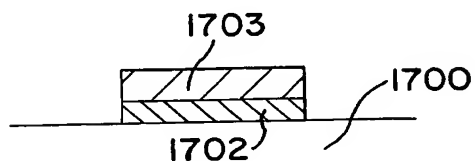


FIG.17(E)

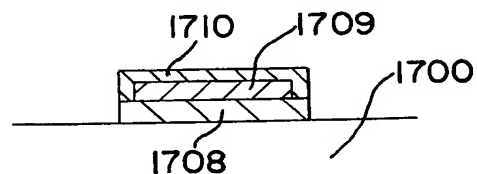


FIG.17(C)

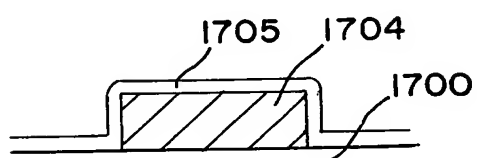


FIG.17(F)

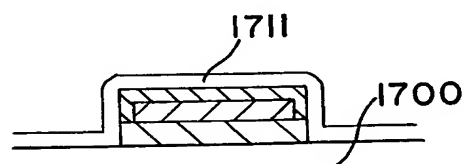


FIG. 18

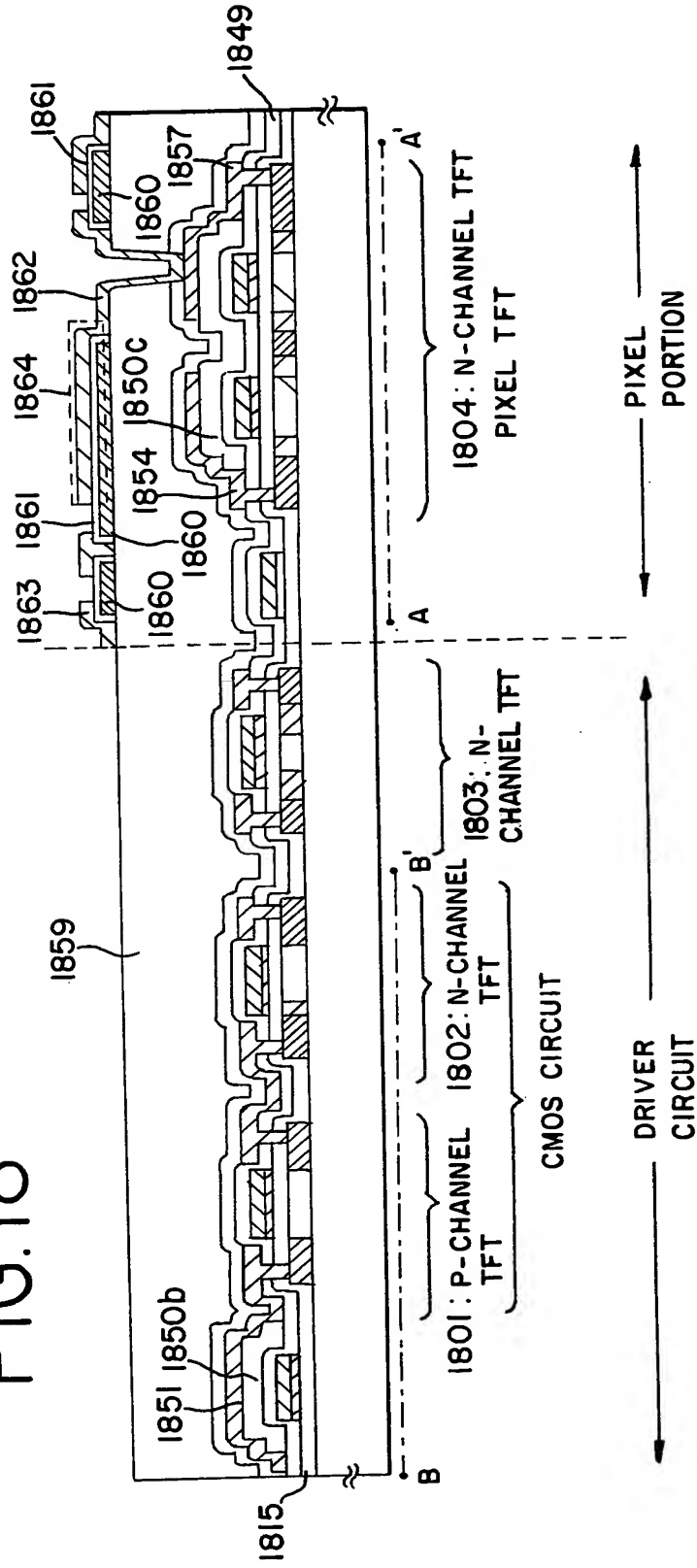


FIG.19(A) FIG.19(B)

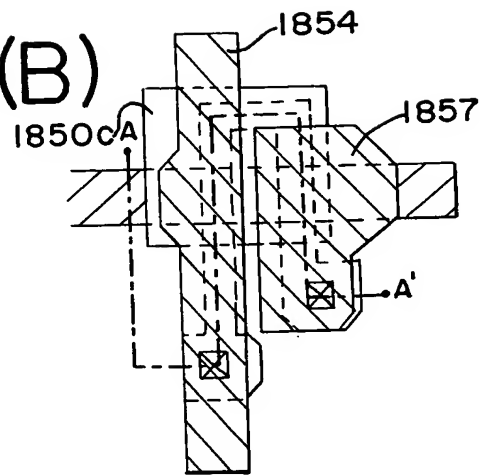
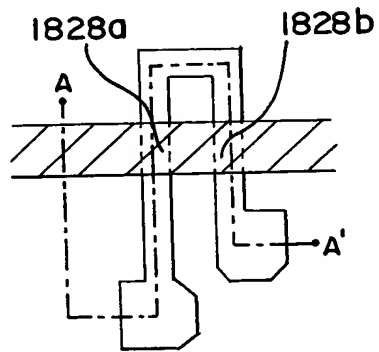


FIG.20(A)

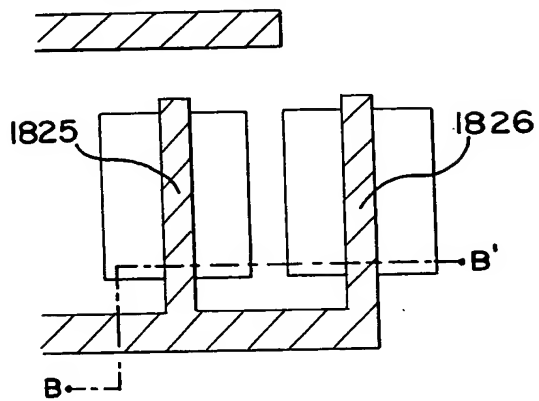


FIG.20(B)

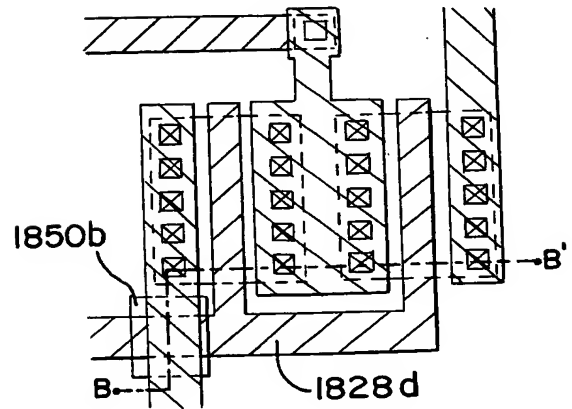
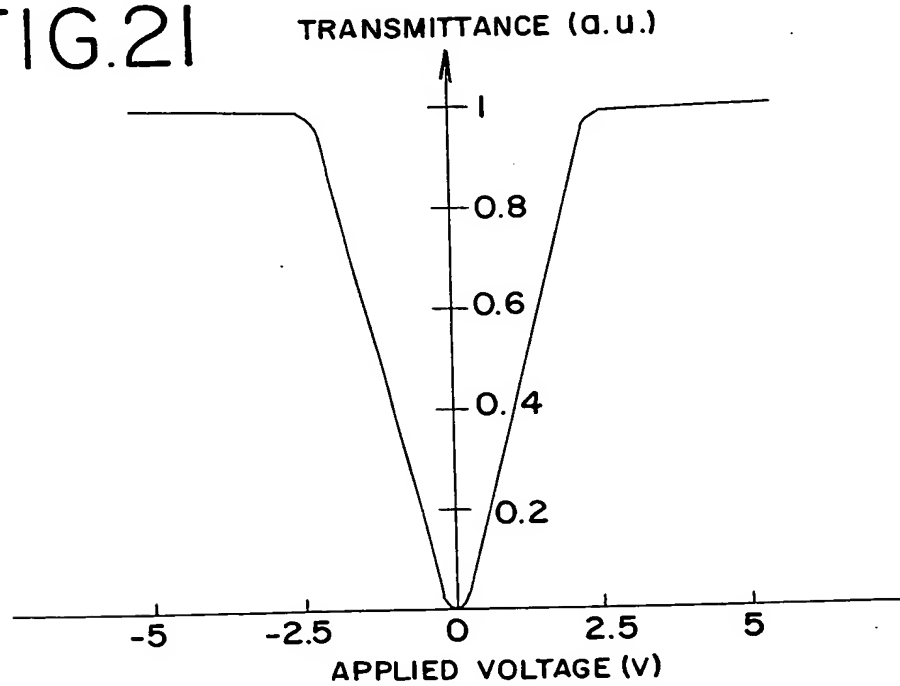


FIG.21



13 Y DIRECTION PERIPHERAL DRIVER CIRCUIT

11 PIXEL PORTION

18a X-DIRECTION SIGNAL LINE

19a POWER SUPPLY LINE

18b X-DIRECTION SIGNAL LINE

19b POWER SUPPLY LINE

12 X DIRECTION PERIPHERAL DRIVER CIRCUIT

16 CURRENT CONTROLLING TFT

17 ORGANIC EL ELEMENT

20a

20b

20c

Y-DIRECTION SIGNAL LINE

FIG.23(A)

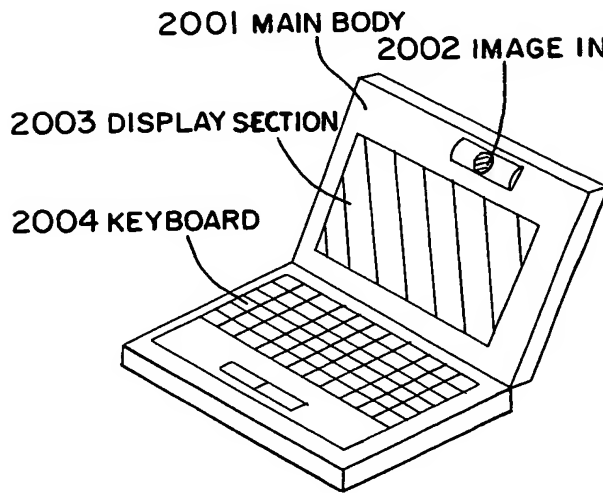


FIG.23(B)

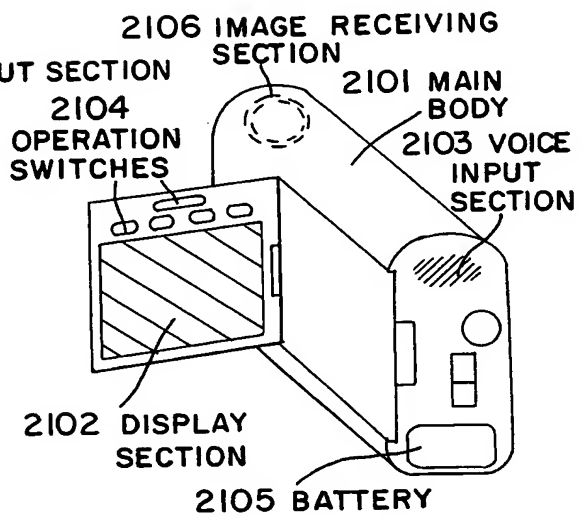


FIG.23(C)

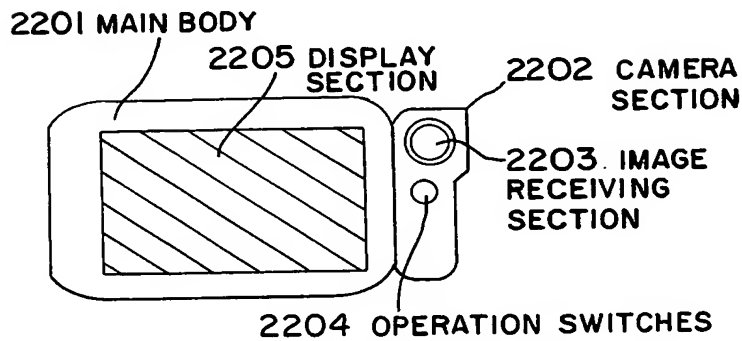


FIG.23(D)

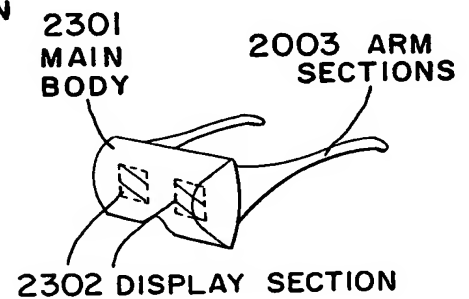


FIG. 23(E)

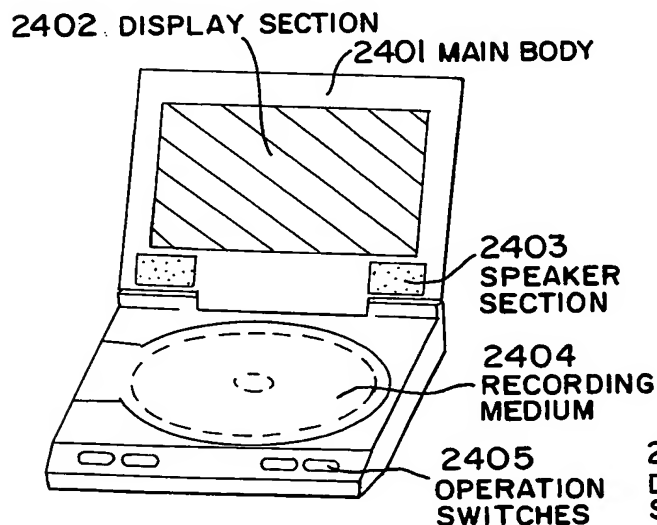


FIG.23(F)

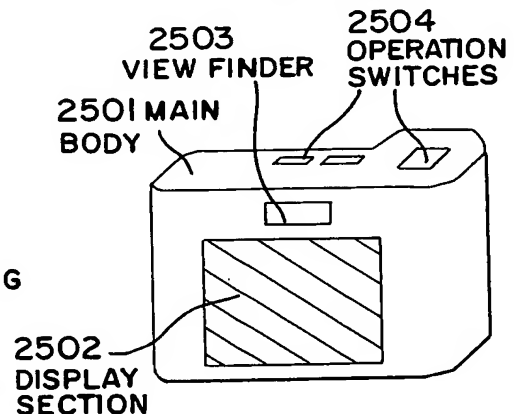


FIG.24(A)

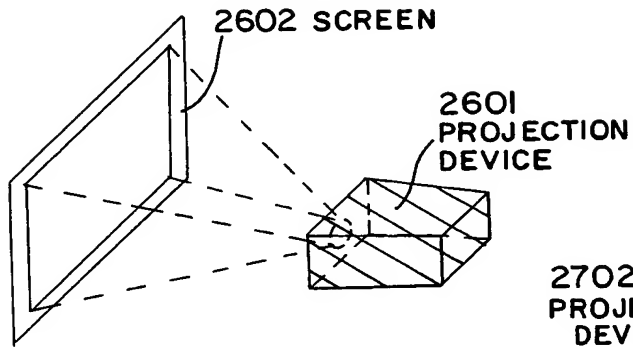


FIG.24(B)

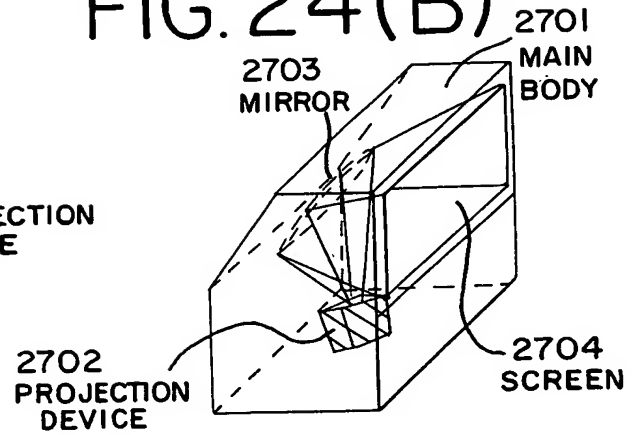


FIG.24(C) PROJECTION DEVICE (THREE-PLATE STYLE) TOWARD SCREEN

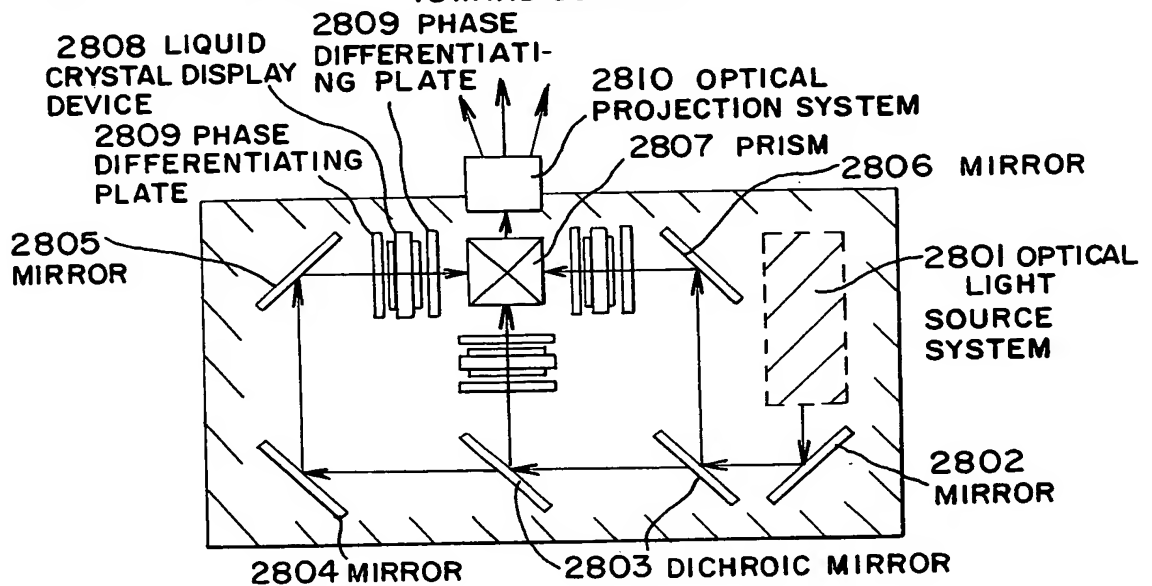


FIG.24(D) OPTICAL LIGHT SOURCE SYSTEM

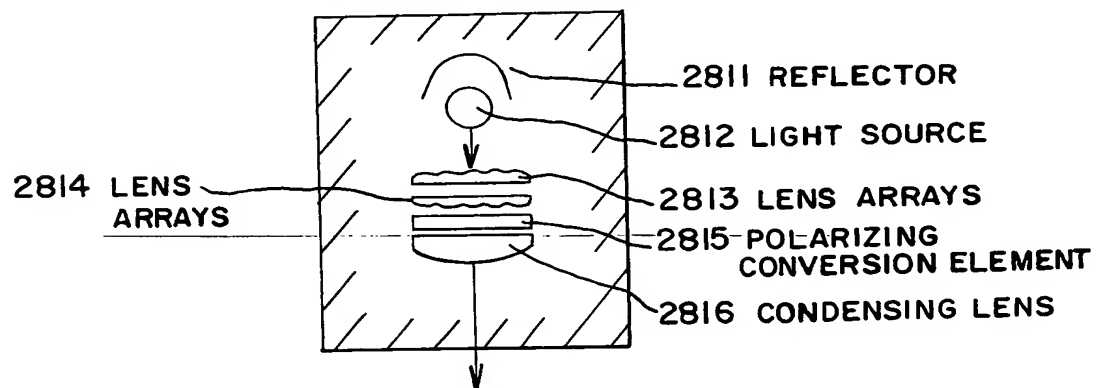


FIG.25

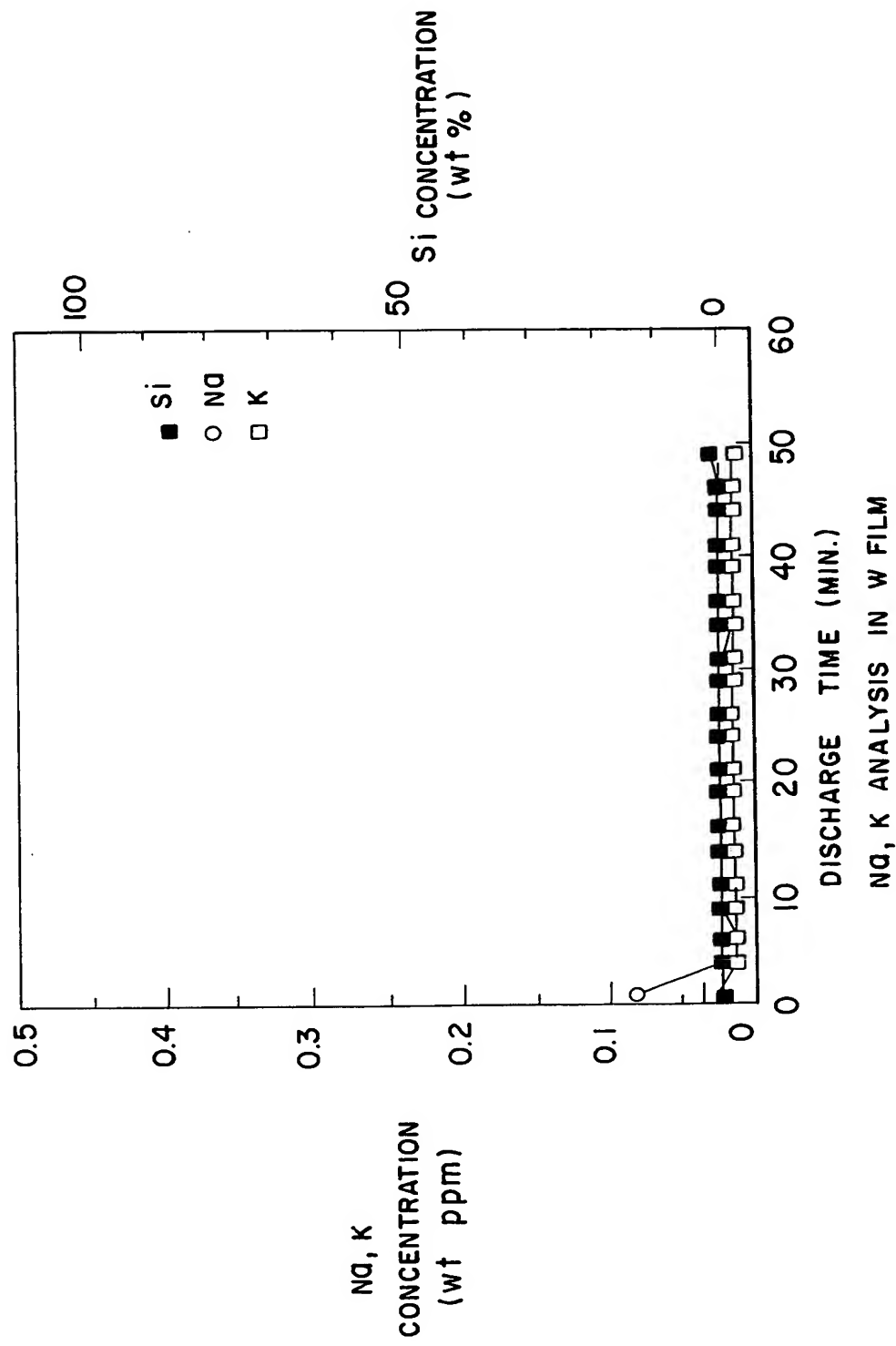


FIG.26(A)

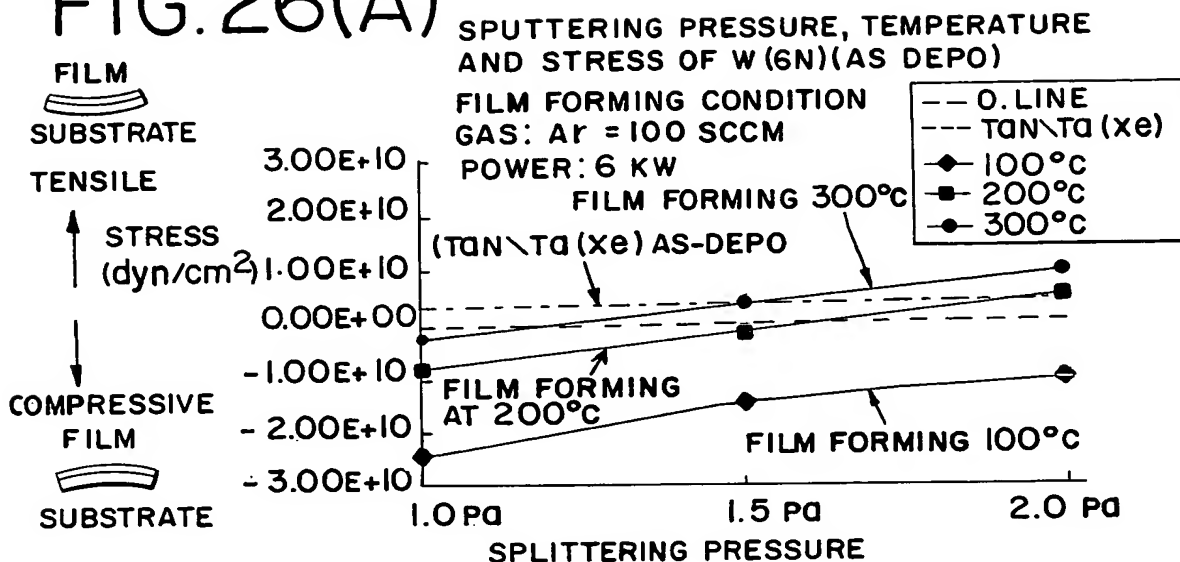


FIG.26(B)

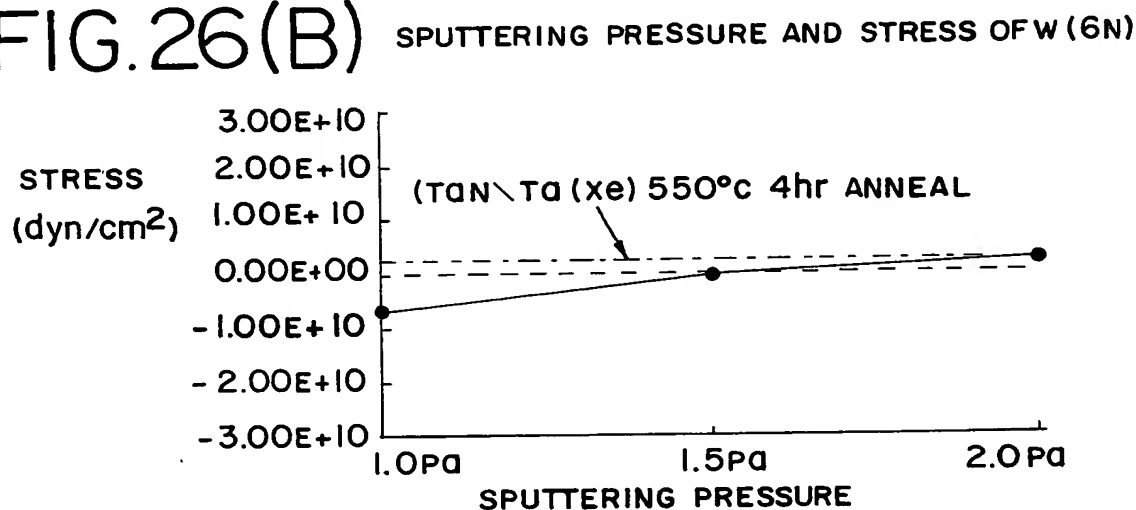


FIG.26(C)

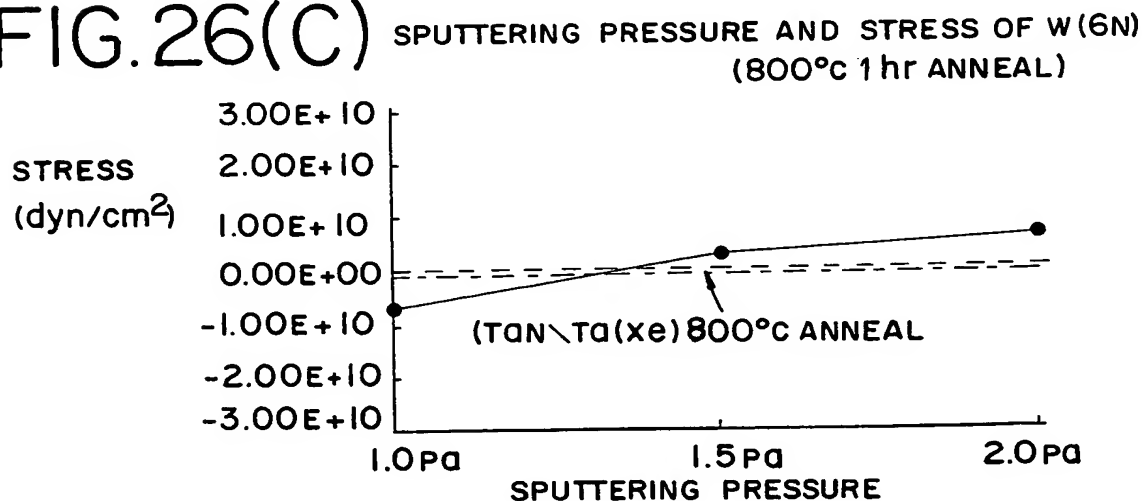


FIG.27(A)

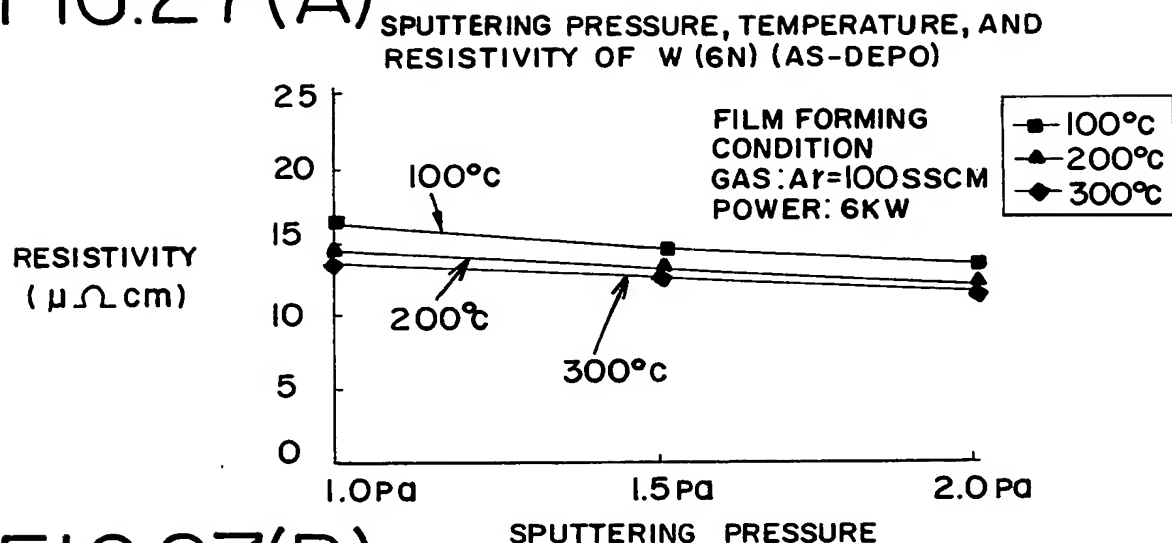


FIG.27(B)

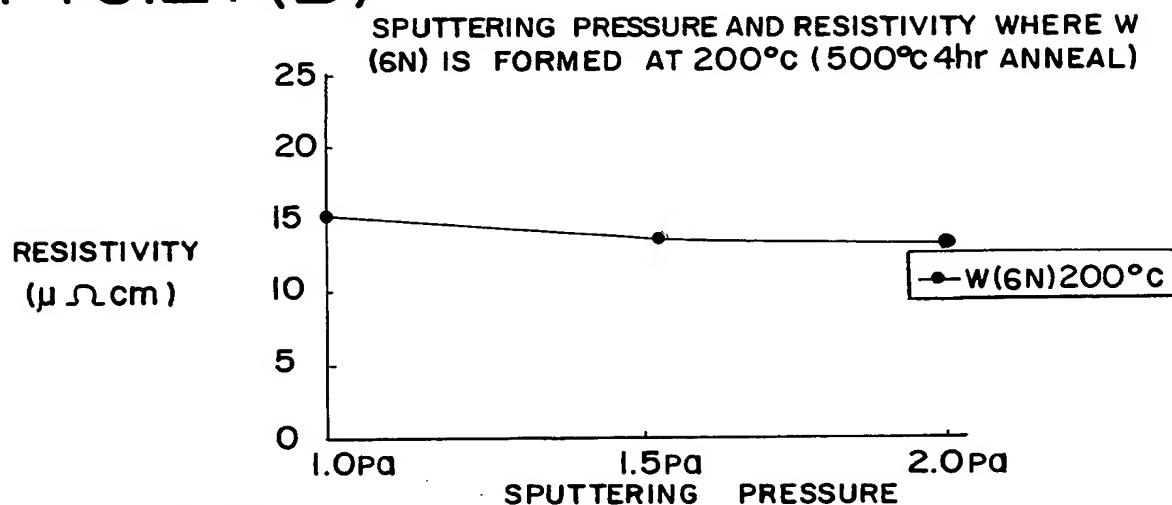


FIG.27(C)

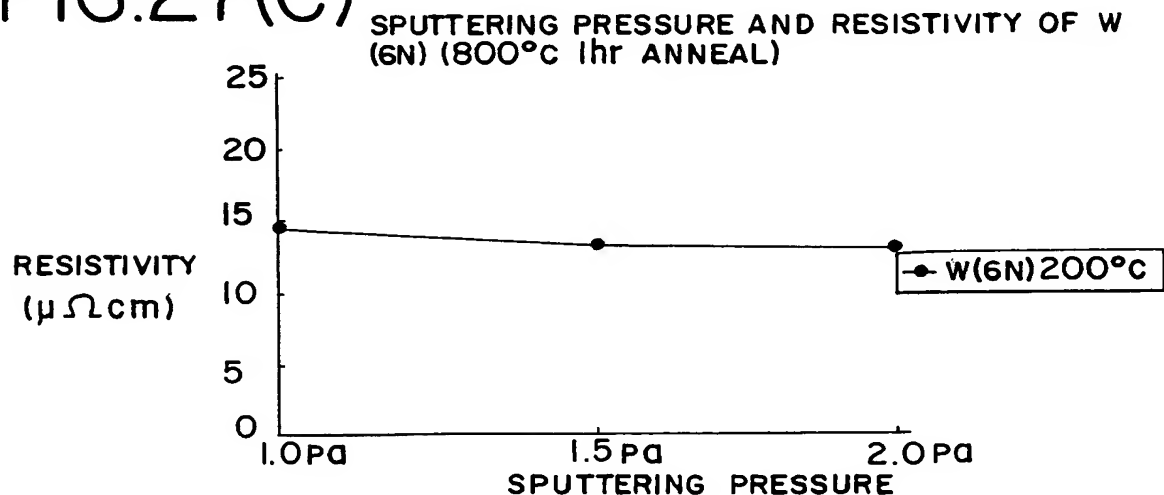


FIG.28(A) TENSILE STRESS

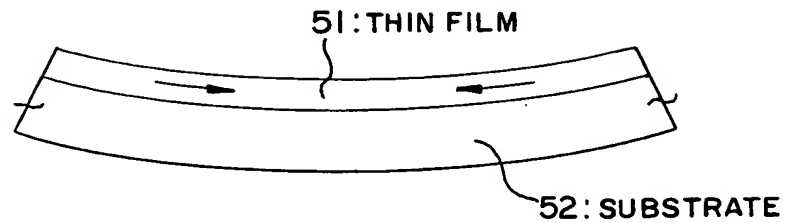


FIG.28(B)

COMPRESSIVE STRESS

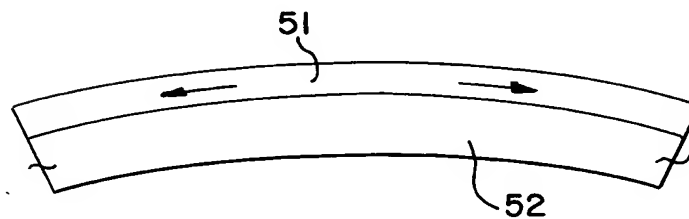


FIG. 29

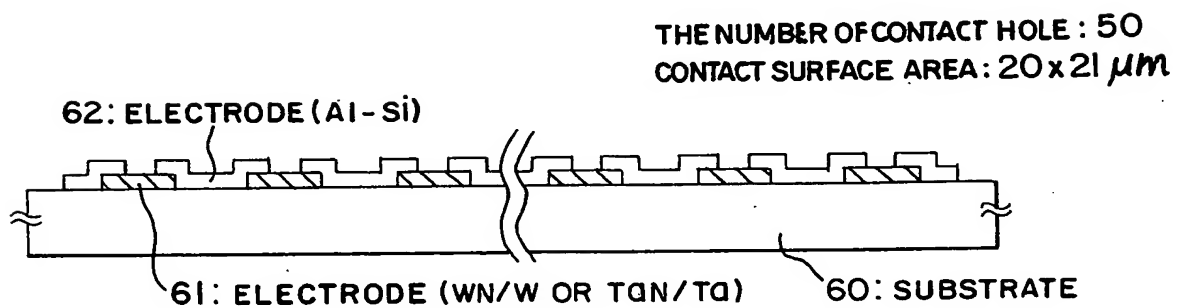


FIG.30

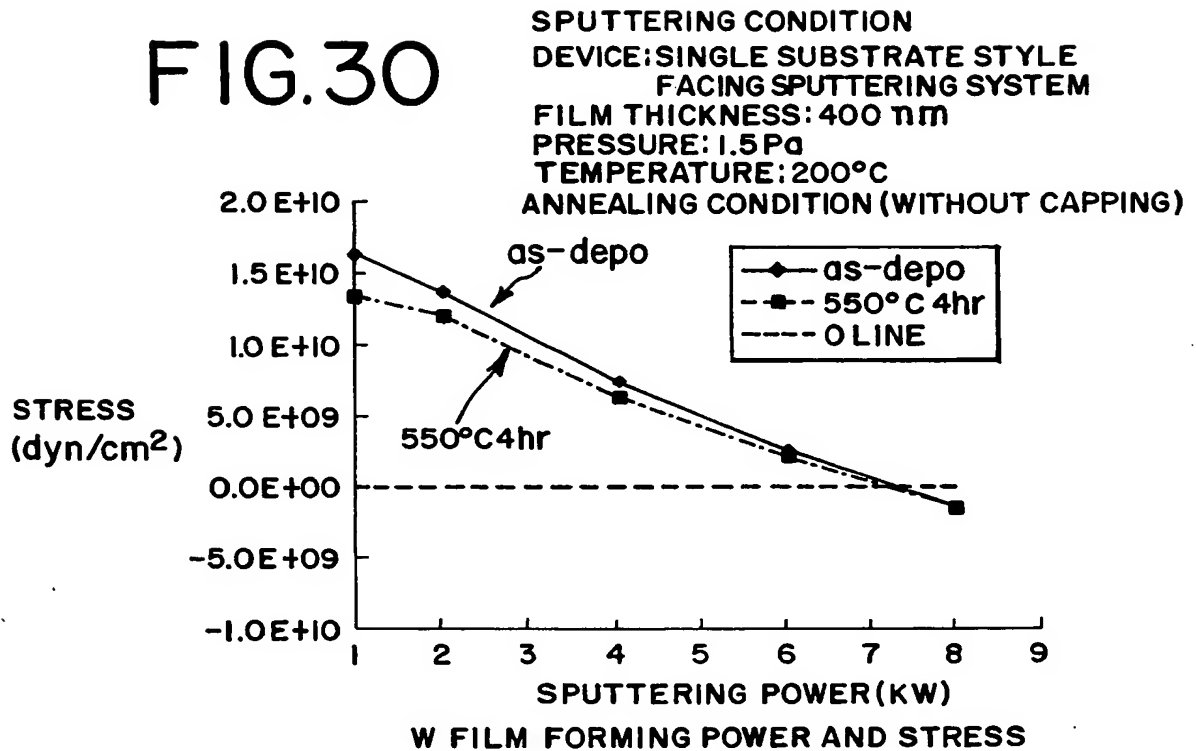


FIG.31

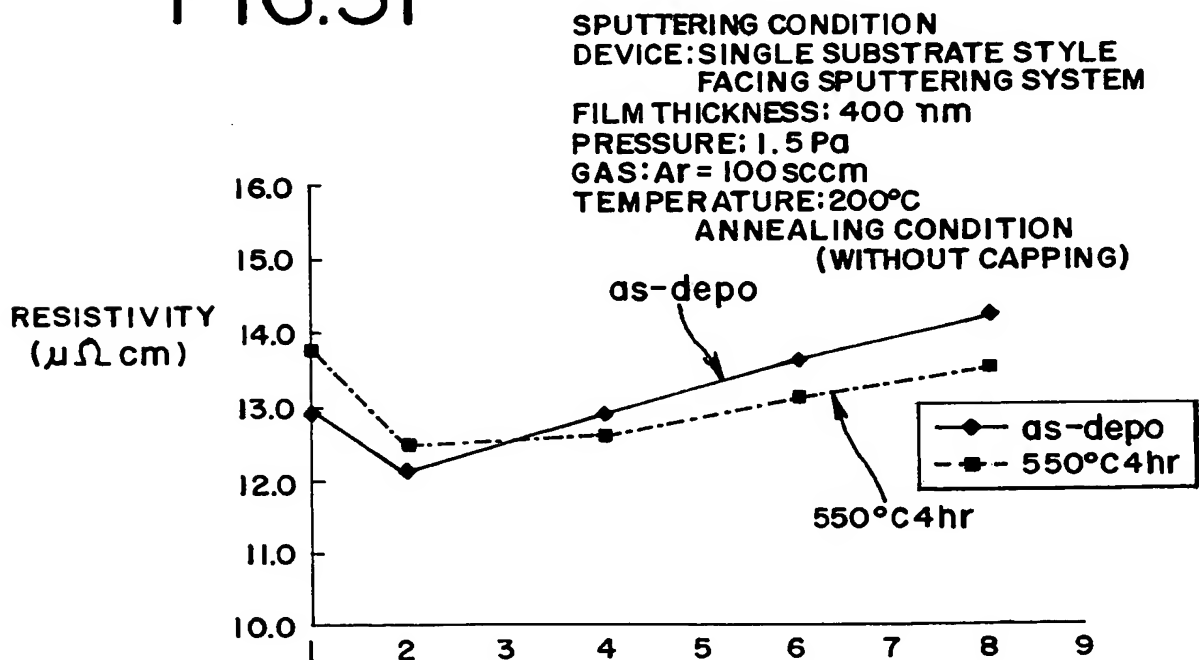


FIG.32

